

What is claimed is:

1. A dual chamber apparatus comprising:
 - a first chamber;
 - a second chamber which is configured to be coupled to said first chamber at an interface, each of said first chamber and said second chamber having a transfer opening located at said interface; and
 - an insulating plate located on one of said first chamber and said second chamber at said interface and configured to have a low thermal conductivity;
 - wherein said first chamber and said second chamber can be independently controlled at different temperatures when said first chamber and said second chamber are coupled together.
2. The dual chamber apparatus as claimed in claim 1, further comprising:
 - at least one alignment device on one of said first chamber and said second chamber; and
 - at least one alignment hole corresponding to each said at least one alignment device on the other of said first chamber and said second chamber.
3. The dual chamber apparatus as claimed in claim 1, further comprising:
 - at least one chamber fastening device on one of said first chamber and said second chamber; and
 - at least one chamber fastening hole corresponding to each said at least one alignment device on the other of said first chamber and said second chamber.
4. The dual chamber apparatus as claimed in claim 1, wherein said first chamber is a chemical oxide removal chamber and said second chamber is a heat treatment chamber.
5. The dual chamber apparatus as claimed in claim 1, further comprising a gate valve assembly for sealing said first chamber from said second chamber.

6. The dual chamber apparatus as claimed in claim 1, wherein said first chamber and said second chamber are essentially evacuated and a seal created between said first chamber and said second chamber is a vacuum seal.

7. The dual chamber apparatus as claimed in claim 1, wherein said insulating plate is located on said first chamber.

8. The dual chamber apparatus as claimed in claim 1, wherein said insulating plate is constructed of Teflon.

9. The dual chamber apparatus as claimed in claim 1, wherein said insulating plate comprises a contact member configured to separate said first chamber from said second chamber by a predetermined distance.

10. The dual chamber apparatus as claimed in claim 9, wherein a surface area of said contact member is substantially smaller than a surface area of said insulating plate.

11. A method for manufacturing a dual chamber system comprising a first chamber and a second chamber, the method comprising:

coupling an insulating plate around a transfer opening of one of said first chamber and said second chamber;

aligning said first chamber with said second chamber at an interface;

coupling said first chamber to said second chamber;

forming a vacuum seal between said first chamber and said second chamber; and controlling a temperature within said first chamber and said second chamber independently when said first chamber and said second chamber are coupled together .

12. The method for manufacturing a dual chamber system as claimed in claim 11, further comprising separating said first chamber and from said second chamber by a predetermined distance.

13. A dual chamber apparatus comprising:
a first chamber;

a second chamber which is configured to be coupled to said first chamber at an interface, each of said first chamber and said second chamber having a transfer opening located at said interface;

an insulating plate located between said first chamber and said second chamber at said interface;

a contact member configured to separate said first chamber from said second chamber by a predetermined distance, the surface area of said contact member being substantially smaller than a surface area of said insulating plate;

at least one alignment structure on one of said first chamber and said second chamber; and

at least one complementary alignment structure corresponding to each said at least one alignment structure on the other of said first chamber and said second chamber.